

CTB-00656

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Product: Selenia

Subsystem: AWS

Dimensions/3Dimensions

Subject: Artifact Evaluation for CE2D Option on Selenia

Dimensions Version 1.10 and 3Dimensions Version 2.1 Systems

Purpose

To provide instructions to the physicist on performing the Artifact Evaluation test for the Contrast Enhanced 2-Dimension (CE2D) option. In Selenia Dimensions Version 1.10 and 3Dimensions Version 2.1 software, the Auto-time functionality has been removed for CE2D. Since the current revision of the QC manual MAN-03706 rev 009 does not reflect these changes, this document provides an alternative procedure for performing the CE2D Artifact Evaluation QC test.

This is the same procedure that the Radiologic Technologist should follow when performing the Artifact Evaluation Test for CE2D.

Scope

This information applies to Selenia Dimensions systems running software version 1.10 and 3Dimensions systems running software version 2.1.

Technical Bulletin (cont.)

Resolution

Perform the Artifact Evaluation QC test, as per the following procedure.



Artifact Evaluation (CE2D Option)

1. Lower the compression device between 5 cm and 7 cm.
2. Make sure that both the Flat Field phantom and the surface of the image receptor are clean. Place the Flat Field phantom on top of the image receptor to cover its active surface.
3. Select the **Flat Field CEDM** view from the Procedure screen on the Acquisition Workstation.
4. Set the exposure technique per the following table:

Table 1: Artifact Evaluation Cu Filter Exposure Techniques (CE2D Option)

Mode	kVp	mAs	Filter	Focal Spot
Manual	28	100	Rh	Large



Note

The CE2D modality is only compatible with Manual and Auto-Filter AEC modes.

5. Acquire an exposure.
6. Select the **Contrast** tab. Select the  button (typically used to show the low-energy image for patient CEDM views) to display the Cu filter exposure.
7. Select the **Actual Pixels** button  to bring the image into full resolution. Examine the entire image for artifacts; use the magnification tool if necessary.



Note

Acquiring an image for artifact evaluation using the Flat Field view sets the image window to 500 and the image level to the exposure index automatically. Artifact evaluation must be performed under these predefined settings.